

## PATENT APPLICATION

## IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of

Docket No: Q92097

Akemitsu IIDA, et al

Appln. No.: National Stage of PCT/JP2004/004521

Confirmation No.: Unknown

Group Art Unit: Unknown

Filed: December 16, 2005

Examiner: Unknown

For: GAS PROCESSING METHOD AND GAS PROCESSING APPARATUS UTILIZING  
OXIDATION CATALYST AND LOW-TEMPERATURE PLASMA

**PRELIMINARY AMENDMENT****MAIL STOP AMENDMENT**

Commissioner for Patents

P.O. Box 1450

Alexandria, VA 22313-1450

Sir:

Prior to examination, please amend the above-identified application as follows on the  
accompanying pages.

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